

Mohammad Mahdavi

List of Publications by Year in descending order

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Version: 2024-02-01

20
papers

131
citations

1307594
7
h-index

1474206
9
g-index

20
all docs

20
docs citations

20
times ranked

129
citing authors

| # | ARTICLE | IF | CITATIONS |
|----|---|-----|-----------|
| 1 | Q Control of an AFM Microcantilever With Double-Stack AlN Sensors and Actuators. <i>IEEE Sensors Journal</i> , 2022, 22, 3957-3964. | 4.7 | 8 |
| 2 | High resolution atomic force microscopy with an active piezoelectric microcantilever. <i>Review of Scientific Instruments</i> , 2022, 93, . | 1.3 | 5 |
| 3 | Modal Actuation and Sensing With an Active AFM Cantilever. <i>IEEE Sensors Journal</i> , 2021, 21, 8950-8959. | 4.7 | 7 |
| 4 | Active Microcantilevers for Dynamic Mode Atomic Force Microscopy. , 2021, , . | | 0 |
| 5 | SOI-MEMS Bulk Piezoresistive Displacement Sensor: A Comparative Study of Readout Circuits. <i>Journal of Microelectromechanical Systems</i> , 2020, 29, 43-53. | 2.5 | 5 |
| 6 | AFM Microcantilever With a Collocated AlN Sensor-Actuator Pair: Enabling Efficient Q-Control for Dynamic Imaging. <i>Journal of Microelectromechanical Systems</i> , 2020, 29, 661-668. | 2.5 | 7 |
| 7 | FPGA-Based Characterization and Q-Control of an Active AFM Cantilever. , 2020, , . | | 4 |
| 8 | High Dynamic Range AFM Cantilever With a Collocated Piezoelectric Actuator-Sensor Pair. <i>Journal of Microelectromechanical Systems</i> , 2020, 29, 260-267. | 2.5 | 13 |
| 9 | A High Dynamic Range AFM Probe with Collocated Piezoelectric Transducer Pairs. , 2020, , . | | 6 |
| 10 | Thin Film Piezoelectric-on-Silicon Elliptical Resonators With Low Liquid Phase Motional Resistances. <i>IEEE Sensors Journal</i> , 2019, 19, 113-120. | 4.7 | 9 |
| 11 | Micro-Resonator-on-Membrane for Real-Time Biosensing. , 2018, , . | | 0 |
| 12 | Highly parallel scanning tunneling microscope based hydrogen depassivation lithography. <i>Journal of Vacuum Science and Technology B:Nanotechnology and Microelectronics</i> , 2018, 36, . | 1.2 | 11 |
| 13 | Microresonator-on-Membrane for Real-Time Mass Sensing in Liquid Phase. , 2018, 2, 1-4. | | 4 |
| 14 | Nano-precision micromachined frequency output profilometer. , 2016, , . | | 3 |
| 15 | Nanoelectromechanical resonant narrow-band amplifiers. <i>Microsystems and Nanoengineering</i> , 2016, 2, 16004. | 7.0 | 25 |
| 16 | Frequency output MEMS resonator on membrane pressure sensors. , 2016, , . | | 3 |
| 17 | MEMS resonant sensors for real-time thin film shear stress monitoring. , 2016, , . | | 3 |
| 18 | Ultra sensitive lorentz force MEMS magnetometer with pico-tesla limit of detection. , 2015, , . | | 7 |

ARTICLE

IF CITATIONS

| # | ARTICLE | IF | CITATIONS |
|----|--|----|-----------|
| 19 | SNR improvement in amplitude modulated resonant MEMS sensors via thermal-piezoresistive internal amplification., 2015,,. | 4 | |
| 20 | Piezoelectric resonant MEMS balances with high liquid phase Q., 2014,,. | 7 | |